



Sheet 1 of 2

Form PTO-1449 (Substitute)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		Attorney Docket Number TEGL-01168US0	Application/Patent Number 10/636,020		
<i>Information Disclosure Statement BY APPLICANT (Use several sheets if necessary)</i>		Applicant/Patent Owner Tue Nguyen					
		Filing/Issue Date August 7, 2003	Group Art Unit 1734				
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Examiner Initial		Patent Number	Issue Date	Inventor(s)	Class	Subclass	Filing Date
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Examiner	<i>Jer</i>		Date Considered	2/06			



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Examiner <i>Jen</i>	Date Considered <i>2/06</i>				
<p>*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</p> <hr/> <p>*1 = Copy not submitted because it was submitted in prior application SN /_____, filed _____, 20_____, relied on under 35 USC §120.</p> <p>**2 = Copy not submitted because it was submitted in prior application SN /_____, filed _____, 20_____, relied on under 35 USC §120.</p>					